

Abstract

A method for evaluating recorded images of wafers is disclosed. The recording of an image of at least one reference wafer is followed by the determination and representation, on a user interface, of the radial distribution of the measured values of the reference wafer as a radial homogeneity function. A radially dependent sensitivity profile is changed while taking into account the measured radial homogeneity function of the reference wafer. At least one parameter of the sensitivity profile is varied whereby a learned sensitivity profile is determined visually from the comparison with the radial homogeneity function.